

Besides PLD, we offer integration or standalone solutions of a wide variety of other deposition techniques such as CVD, sputtering, evaporators and various types of ion source solutions. These tools can be directly integrated in a PLD

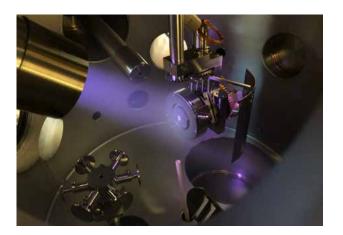
system solution or have a dedicated vacuum chamber within a cluster setup. Furthermore we are highly experienced in the integration of various analysis tools in thin-film depositions systems such as RHEED, QCM and RGA.

Laser CVD

Demcon TSST in collaboration with Coherent developed a unique custom designed CVD system, handling up to 100x100mm substrates. Demcon TSST developed the full CVD gas handling hardware and software control, ensuring full control over all steps during the CVD process, taking into acount all required and necessary safety features. Our software allows to program scanning patterns of the large sample with respect to the excimer laser beam to activate surfaces.

PVD cluster systems solutions

Demcon TSST offers customised cluster system solutions where PLD is combined with other deposition techniques such as a dedicated sputter or e-beam evaporation chamber. Both system are connected through a loadlock, making in-vacuum sample transfer possible. In this way, both techniques can be combined, ensuring the best and cleanest process conditions for both techniques.



Options on Demcon TSST system solution include

- Sample biasing
- Ozone generator
- Atom/ion/plasma sources
- QCM
- RGA

